

NOV 01 2006

Docket No. 212/543

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

In re Application of:

Darymple, et al.

Serial No.: 10/754,360

Filed: January 8, 2004

For: Devices and Methods for
Optical Endpoint Detection During
Semiconductor Wafer Polishing

Art Unit: 1763

Examiner: MacArthur, Sylvia

AMENDMENT AFTER ALLOWANCE (37 CFR 1.312)

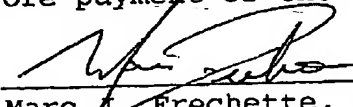
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Enclosed please find Applicants' Information Disclosure Statement. The reference was cited in the International Search Report, but was omitted from the IDS filed on July 11, 2006 due to clerical error. We have reviewed the reference and believe it to be cumulative. The amendment has been filed after receipt of the Notice of Allowance, but before payment of the Issue Fee.

Date: November 1, 2006

By:


Marc J. Frechette, Esq.
Reg. No. 49060

Certificate of facsimile transmission

I hereby certify that this response (along with any paper referred to as being attached or enclosed) is being facsimile transmitted to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 at the facsimile telephone number indicated below.

Fax No. 571 273 8300
Date: November 1, 2006


Marc J. Frechette, Esq.